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LIST OF PUBLICATIONS CITED BY APPLICANT		Attorney Docket No. SEL 203		Serial No. Not Assigned		
		Applicant Setsuo NAKAJIMA et al				
		Filing Date Herewith		Group		
U.S. PATENT DOCUMENTS						
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
OTHER PUBLICATIONS (Including Author, Title, Date, Pertinent Pages)						
SK	Nakabu, S. et al, "The Development of Super-High Aperture Ratio with Low Electrically Resistive Material for High-Resolution TFT-LCDs," 1999 SID International Symposium Digest of Technical Papers, pp. 732-735, 1999.					
EXAMINER: Shounanagella				DATE CONSIDERED: 3-22-02		
*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP form. Draw line through citation if not in conformance and not considered. Include a copy of this form with the next communication to applicant.						

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